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TRANSMITTAL FORM (to be used for all correspondence after initial filing)	Application Number	10/733,181
	Filing Date	12/10/2003
	First Named Inventor	Manning et al.
	Art Unit	2834
	Examiner Name	Unknown
Total Number of Pages in This Submission	Attorney Docket Number	MI22-2295

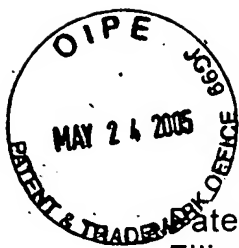
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SIGNATURE OF APPLICANT, ATTORNEY, OR AGENT	
Firm or Individual	David G. Latwesen, Ph.D., Reg. No. 38,533 Wells St. John, P.S.
Signature	
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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Patent Application Serial No. 10/733,181
Filing Date December 10, 2003
Inventor H. Montgomery Manning et al.
Assignee Micron Technology, Inc.
Group Art Unit 2812
Examiner Unknown
Attorney Docket No. MI22-2295
Customer No. 021567
Title: Semiconductor Constructions, and Methods of Forming Capacitor Devices

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

References -- See Attached Form PTO-1449

In compliance with 37 C.F.R. §§ 1.56, 1.97 and 1.98, your attention is directed to the United States patents and other references listed on the attached Form PTO-1449. No admission is made regarding whether all the submitted references are prior art.

EV550717282

This Supplemental Information Disclosure Statement is being filed within three months of the filing date of the application or before the mailing of a first Office Action on the merits, whichever occurs last. Therefore, no fee is believed to be required. However, in the event that a fee is required for filing this Supplemental Information Disclosure Statement, please charge the fee specified under 37 C.F.R. § 1.17(p) to Deposit Account No. 23-0925.

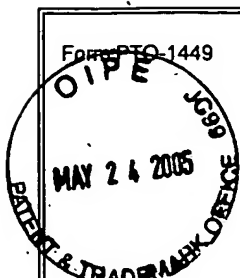
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Dated: _____

5/24/05

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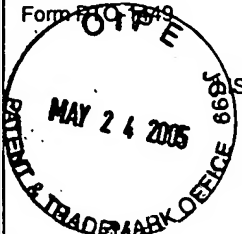
David G. Latwesen, Ph.D.
Reg. No. 38,533

Form PTO-1449 	U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-2295	SERIAL NO. 10/733,181
	LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)			
	APPLICANT: H. Montgomery Manning et al.			
			FILING DATE December 10, 2003	GROUP 2812

U.S. PATENT DOCUMENTS							
*Examiner's Initials		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA			EV550717282			
	AB						
	AC						

FOREIGN PATENT DOCUMENTS								
		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
	AD	DE 4447804	1/2002	Germany			Abstract	
	AE							

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)			
	AF		J. P. O'Sullivan et al., <i>The morphology and mechanism of formation of porous anodic films on aluminium</i> , PROC. ROY. SOC. LOND. A, Vol. 317, pp. 511-543 (1970)
	AG		S. Shingubara, <i>Fabrication of nanomaterials using porous alumina templates</i> , J. NANOPARTICLE RES., Vol. 5, pp. 17-30 (2003).
	AH		S. Tan et al., <i>High Aspect Ratio Microstructures on Porous Anodic Aluminum Oxide</i> , IEEE, pp. 267-272 (1995).
	AI		J. Liang et al., <i>Nonlithographic Fabrication of Lateral Superlattices for Nanometric Electromagnetic-Optic ...</i> IEEE J. SELECTED TOPICS IN QUANTUM ELECTR., Vol. 8, No. 5, pp. 998-1008 (Sept/Oct 2002).
	AJ		V. V. Konovalov et al., <i>Chemistry of Materials</i> , CHEM. MATER., Vol. 11, No. 8, pp. 1949-1951 (August 1999).
	AK		H. Masuda et al., <i>Highly ordered nanochannel-array architecture in anodic alumina</i> , App. Phys. Lett, Vol. 71, No. 19, pp. 2770-2772 (November 1997).
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	APPLICANT: H. Montgomery Manning et al.		FILING DATE December 10, 2003	

U.S. PATENT DOCUMENTS							
*Examiner's Initials		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA						
	AB						
	AC						
	AD						
	AE						
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EV550717282

FOREIGN PATENT DOCUMENTS								
		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
	AJ							
	AK							
	AL							

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)			
	AM		D. Crouse et al., <i>Self-Assembled Nanostructures Using Anodized Alumina Thin Films for Optoelectronic Applications</i> , IEEE, pp. 234-235 (1999).
	AN		A. Nadeem et al., <i>Fabrication of Microstructures Using Aluminum Anodization Techniques</i> , pp. 274-277 (pre-2004).
	AO		C. Y. Liu et al., <i>Ordered anodic alumina nanochannels on focused-ion-beam-prepatterned aluminum surfaces</i> , Appl. Phys. Lett., Vol. 78, No. 1, pp. 120-122 (January 2001).
EXAMINER		DATE CONSIDERED	
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